

AMENDMENTS TO THE CLAIMS:

Please cancel claims 1-10, without prejudice. Please add new claims 11-17, as shown below.

This listing of claims will replace all prior versions and listings of claims in the Application:

Claim 1 - 10 (cancelled)

Claim 11 (new): A plasma processing apparatus in which particulate dust is generated when a substrate is processed by plasma in a high vacuum enclosure, and a reactive material is introduced into the high vacuum enclosure, the apparatus comprising:

a plasma generating electrode and at least one particulate collecting electrode, wherein the said at least one collecting electrode has a storage space for storing particulates collected therein, said collecting electrode further having openings communicating between the storage space and an inside of the high vacuum enclosure, said collecting electrode being provided adjacent the substrate been processed;

an electric potential source for applying an electric potential of direct current or alternating current to the collecting electrode; and

at least one particulate drawing electrode, which is insulated from said collecting electrode, for applying an electric potential higher than the electric potential of said collecting electrode, provided around said openings of said collecting electrode.

Claim 12 (new): The processing apparatus according to Claim 11, wherein said collecting electrode is in a continuous or discontinuous ring shape and surrounds the substrate being processed.

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Claim 13 (new): The processing apparatus according to Claim 11, wherein said openings are provided on an inner periphery of said collecting electrode.

Claim 14 (new): The processing apparatus according to Claim 11, wherein said collecting electrode is arranged at a position having substantially the same height as the height of the substrate being processed, and said openings are formed on an upper surface of the collecting electrode.

Claim 15 (new): The processing apparatus according to Claim 11, and further comprising a support mechanism for supporting and moving said collecting electrode relative to said substrate being processed in said high vacuum enclosure.

Claim 16 (new): The processing apparatus according to Claim 11, and further comprising an exhaust mechanism for exhausting gas and particulates in said storage space to an outside of the high vacuum enclosure.

Claim 17 (new): The processing apparatus according to Claim 11, wherein said collecting electrode is freely detachable.

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